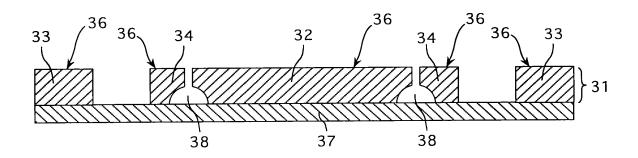


FIG. 2b



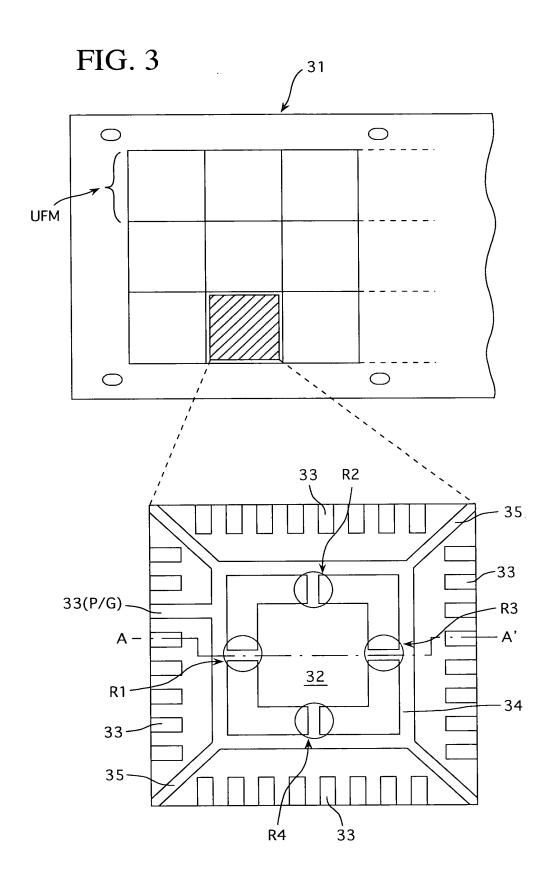


FIG. 4a

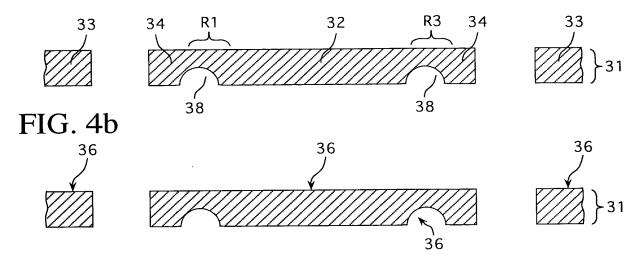
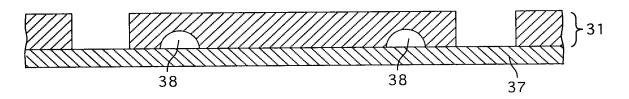
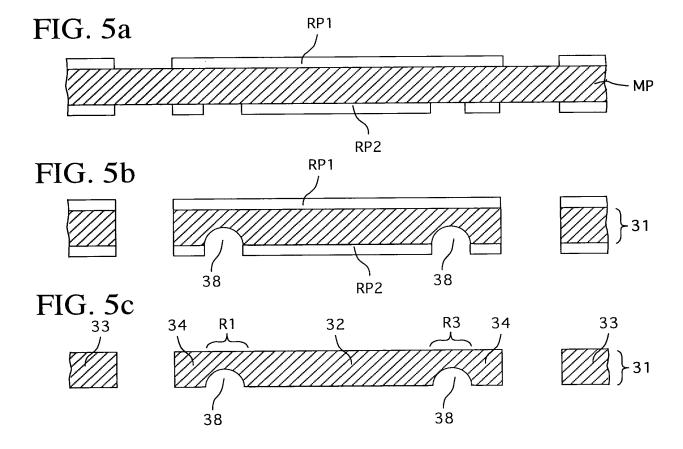
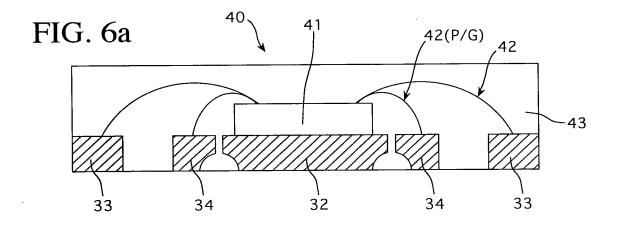


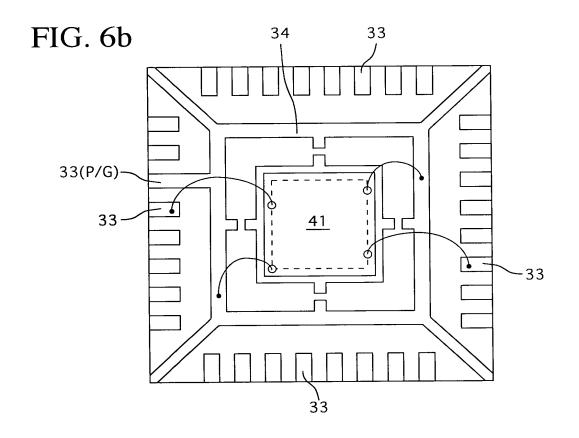
FIG. 4c



30′







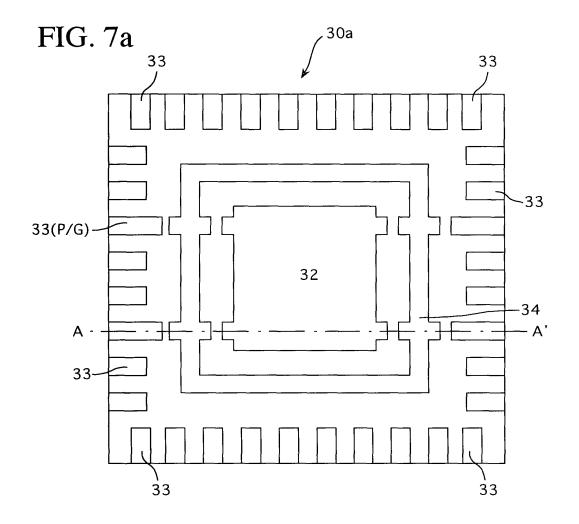
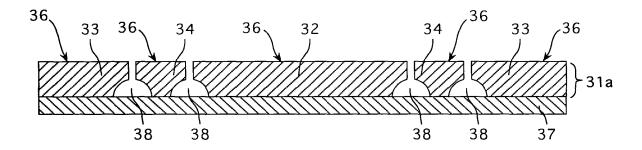
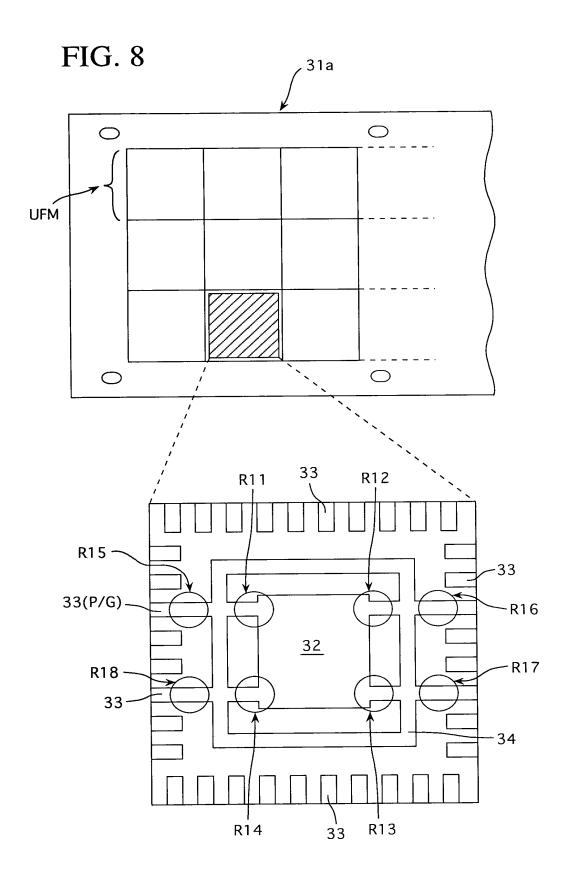
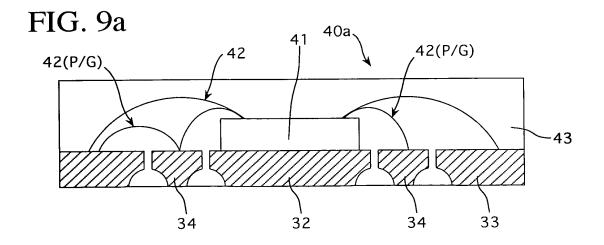
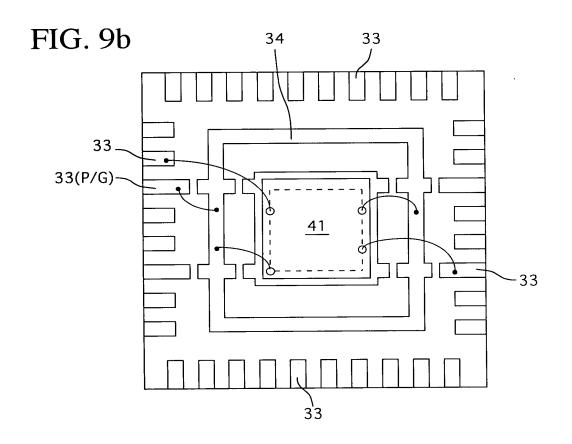


FIG. 7b









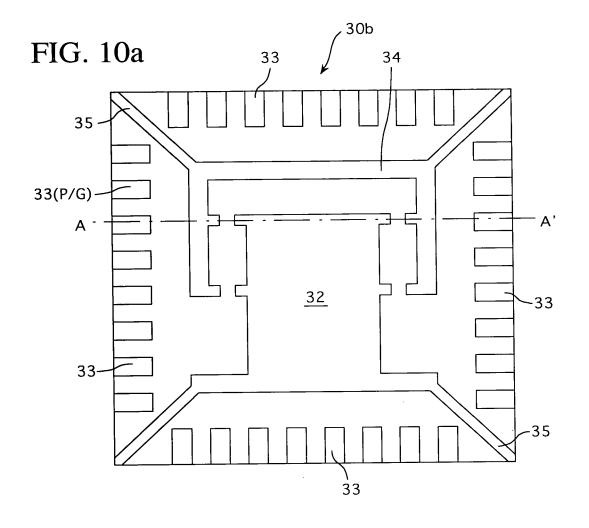


FIG. 10b

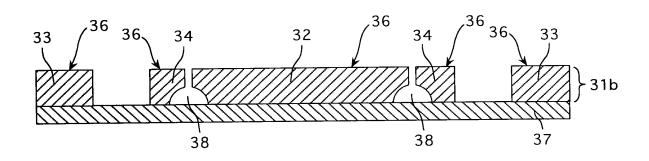


FIG. 11 31b 0 0 UFM 0 \bigcirc 33 R21 R22 - 35 33(P/G)--33 -34 <u>32</u> R24-- R23 33-35-33

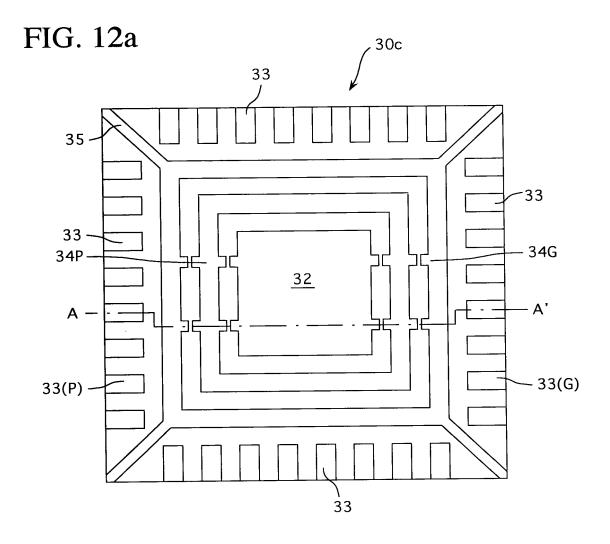
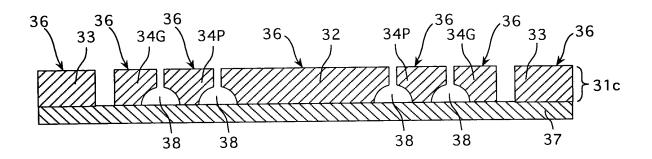


FIG. 12b



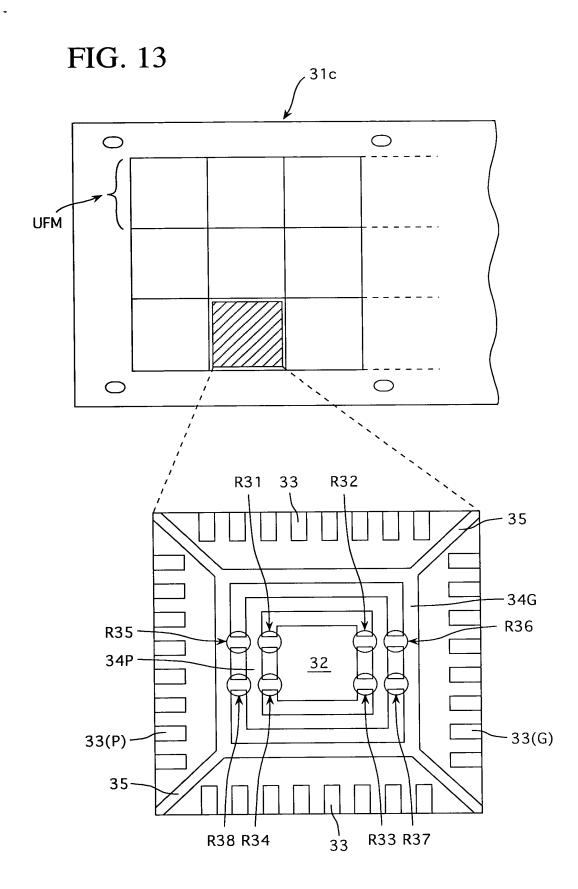


FIG. 14a

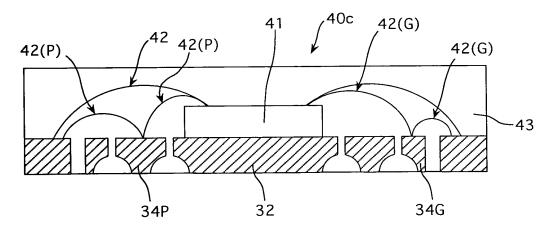
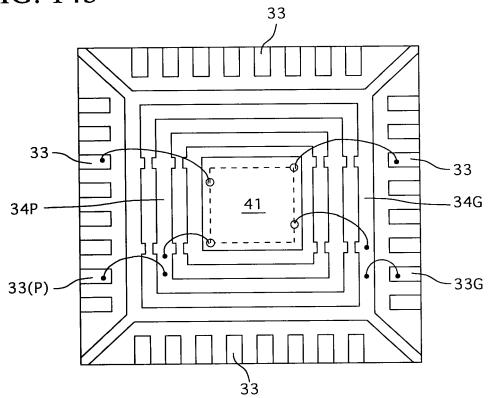


FIG. 14b



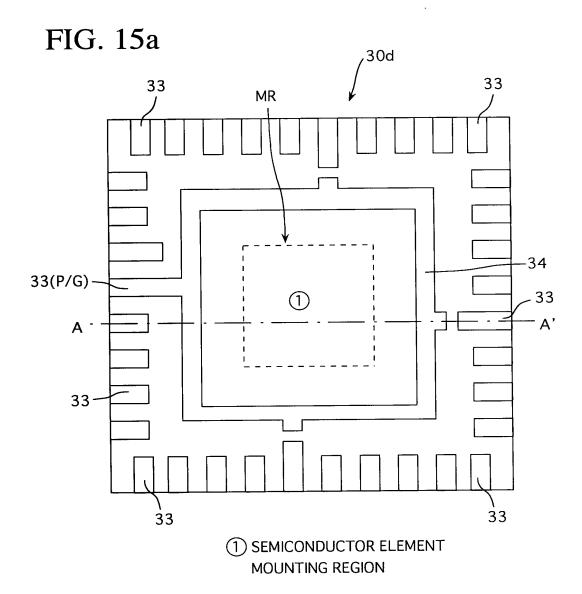
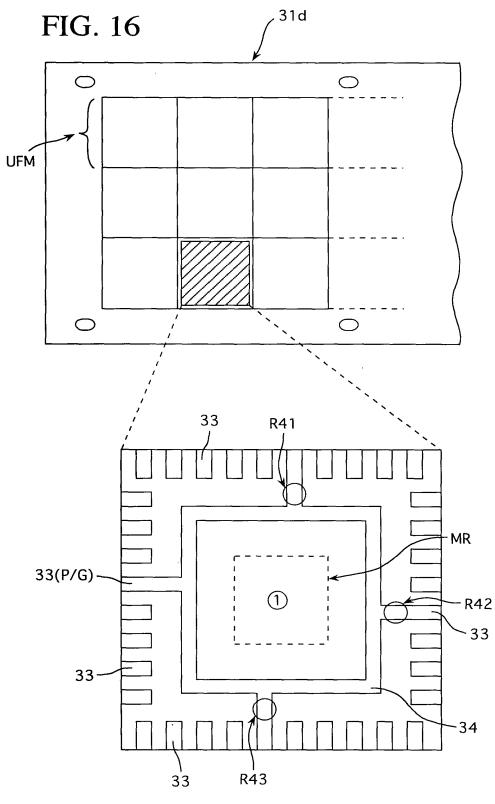


FIG. 15b



1 SEMICONDUCTOR ELEMENT MOUNTING REGION

FIG. 17a

40d

41

42(P/G)

43

33

34

34

33

